2001 - 0097793

	(19) (12)		(KR) (A)	
(51) 。Int. CI. ⁷ H01J 1/70			(11) (43)	2001 - 0097793 2001 11 08
(21) (22)	10 - 2000 - 0022172 2000 04 26			
(71)	2	95	202	
(72)	2	95	202	
	22	220	110 4	
	931		107 303	
	36 - 22	2/4		
(74)				
:				
(54)				

2 , 가가 , , (BN) . 가

1

1 < 10... 11... 1 13... 12, 18... 14... 15... 16... 2 17... 19... (PDP) , (大) 가 가 가 가 (LCD) (Direct Current) (A Iternative Current) (charges) (A C type), (hybrid type) . (DC type) (wall - charge) (Sustaining)

- 2 -

(Common) 1 (10), (10) (12) , 1 (11) , 1 (11) (12)(10) (14) (13) (19) (19)가 (18)18) 2 가 (19) (14) (15) (16)2 (16) 2 (17) (1 (17) 2 가 8) (18)1 (17) 가 (18) (11) 가 가 가 가 (18)가 가 (17) 가 가 2 SrO+CaO, BaO+CaO, SrBaO, MgSrO (18)(19)CaSrO (潮解性) , 2 MgO . MgO Mg(OH)₂ , MgO 가 (crack)

, 2 , 가 가 , , , (BN)

, (BN)

- 3 -

```
t - BN
                                                     a - BN
                                                                       c - BN
  c - BN
    , t - BN, a - BN
                                                                         MgO, SrO, CaO, BaO, MgSrO, CaSr
0
     SrBaO
                                      2
       SrO+CaO, BaO+CaO, SrBaO, MgSrO
                                               CaSrO
                                                                             MgO
                                           가
                                                      가
                                   , 2
                                                         가
                                                                         (Handbook of refractory carbides a
nd nitrides(Hugh O. Pierson), Synthesis and properties of boron nitride(John J. Pouch et.))
                                           (crack)
                                      h - BN(hexagonal boron nitride), c - BN(cubic boron nitride)
  c - BN
                                    (Ion assited pulsed laser deposition of cubic boron nitride films, T.A.F
riedmann et al., 76(5), 3088, 1994).
        sp^2
                   가
                                                                 가
h - BN
        sp^3
                  가
                                                                  가
c - BN
h-BN c-BN
                                                            w - BN(wurtzitic BN), t - BN(turbostratic BN), a
- BN(amorphous BN)
                                 h-BN c-BN
                                                                    w - BN, t - BN, a - BN
가
            c - BN
                                                  가 8GPa
w - BN, t - BN, a - BN
c-BN
                                                                                                        c-B
                                                , t - BN, a - BN
Ν
```

 $MgO,\,SrO,\,CaO,\,BaO,\,MgSrO,\,CaSrO$

```
SrBaO
                               1
                                                                                               2
                               2
                                                    c - BN
                                                                                   1
                                                                                                     2
                                                                                  1
                                         , t - BN, a - BN
                                                              ΒN
                                                                    (Ion plating) ,
         (e - beam evaporation),
                                        (sputtering) ,
                                                                                                     (las
er ablation)
                         (Ion beam)
                                                                  (Ion beam deposition) ,
(Ion beam assisted deposition)
                                                                                                    가
                                                                             (Handbook of ion beam proces
sing technology(Jerome J. Cuomo et.), Synthesis and properties of boron nitride(John J. Pouch et.)).
h - BN
                                                            가
                                                                       )
                                     가
                                                 가
                                                                                                     가
                                                          h - BN
      가
             가
                         가
                                                                                                       가
                                                                  가 150eV
                             가 150
                                                                                            , t - BN
            c - BN
                           가 150
                                                                                                          (c
rack)
(57)
       1.
2
                                                           가 가
                                             (BN)
       2.
```

- 5 -

가 8GPa

1

c - BN , 1

- 6 -

6 ,

1

